| Application Number: | 101 | 10798331 | | | | | | |
|---|-----|--|----------|--------|-------------------------|--|--|--|
| Filing Date: | 12- | 12-Mar-2004 | | | | | | |
| Title of Invention: | | METHOD FOR MANUFACTURING SPUTTER-COATED SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING CHAMBER WITH SUCH SOURCE | | | | | | |
| First Named Inventor/Applicant Name: | Sta | Stanislav Kadlec | | | | | | |
| Filer: | Ro | Ronald J. Shore/Elizabeth Lee | | | | | | |
| Attorney Docket Number: | 63 | 635.43483X00 | | | | | | |
| Filed as Large Entity | • | | | | | | | |
| Utility under 35 USC 111(a) Filing Fees | | | | | | | | |
| Description | | Fee Code | Quantity | Amount | Sub-Total in USD(\$) | | | |
| Basic Filing: | | | | | | | | |
| Pages: | | | | | | | | |
| Claims: | | | | | | | | |
| Miscellaneous-Filing: | | | | | | | | |
| Petition: | | | | | | | | |
| Patent-Appeals-and-Interference: | | | | | | | | |
| | | | | | | | | |
| Post-Allowance-and-Post-Issuance: | | | | | | | | |

Publ. Fee- early, voluntary, or normal

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
|-----------------------------------|----------|----------|--------|-------------------------|
| Extension-of-Time: | | | | |
| Miscellaneous: | | | | |
| Printed copy of patent - no color | 8001 | 4 | 3 | 12 |
| | Tot | 1822 | | |